

System Specifications

- **Resolution (Secondary Electrons)**
 - 4 nm, Tilt = 0, V = 1kV
- **Magnification**
 - 100 X – 200,000 X
- **Accelerating Voltage**
 - 0.7 – 15 kV
- **Optical Microscope**
 - 110 X
- **Repeatability**
 - 5 nm (3-Sigma) or 1%
- **Wafer Size**
 - 200 mm
- **Gun**
 - Thermal Field Emission
- **Measurement Modes**
 - Manual or Automatic using pattern recognition
 - Cursor and line profile measurement
- **Tilt**
 - 0 – 60 degrees
- **Rotation**
 - 360 Degrees
- **Mask Inspection**
 - 6 inch mask holder
- **Sample Cross-sections**
 - 10 Stubs max
 - Max size 10mm x 19mm x 1.2mm
- **Software**
 - Multi-point Measurement
 - Image Archiving
- **Low Voltage Operation**
 - 0.7 – 1 kV
- **Automated CD Measurements**
- **Automatic Functions**
 - Automatic Focus Correction (AFC)
 - Automatic Astigmatism Correction (AST)
 - Automatic Brightness & Contrast Control (ABCC)
 - Automatic Image Centering (RISM)
 - Automatic Beam Blanking

- **Energy Dispersive Spectroscopy (EDS) Detector**
 - Oxford EDS Detector
 - Aztec Software
 - EDS Spectra Data Collection

